

Notice of References Cited	Application/Control No. 10/687,519	Applicant(s)/Patent Under Reexamination TRUSKETT ET AL.	
	Examiner B. Chen	Art Unit 1762	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,334,960 B1	01-2002	Willson et al.	216/52
*	B	US-6,446,933 B1	09-2002	Westmoreland, Donald L.	249/114.1
*	C	US-2003/0022072 A1	01-2003	Campi et al.	430/5
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	M	US-			

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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.